



03500.015262

QF-1762
JFW
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
TAKESHI SHISHIDO ET AL.) : Examiner: M. Padgett
Application No.: 09/822,191) : Group Art Unit: 1762
Filed: April 2, 2001) :
For: EXHAUST PROCESSING METHOD,)
PLASMA PROCESSING METHOD :
AND PLASMA PROCESSING)
APPARATUS : August 25, 2004

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

a) Introductory Comments

In response to the Office Action date May 25, 2004, kindly amend the subject application as follows.

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

August 25, 2004
(Date of Deposit)

Jason M. Okun
(Name of Attorney for Applicants)


Signature

August 25, 2004

Date of Signature